



Electric field measurement in LGAD and update in RASER

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- Electric field measurement in Si LGAD
- Irradiation simulation for Si strip and SiC planar detector
- Summary and Plan

Si LGAD and experimental set-up



- LGAD Tpye3.2 fabricated by HPK
- Key parameters in RASER:

 1.3×1.3 mm² size, 50 µm thick p bulk doping 1.0×10^{12} cm⁻³ p+ doping 2.0×10¹⁶ cm⁻¹⁶

-table

LGAD

y-table

Oscilloscope

RASER simulation



Field measurement: velocity profile

- Main trend method
- for electric field measurement
- Use instant signal near the laser injection time
- Original and gain signal mixed...

$$v_e(t) + v_h(t) = \mu_e[E(z_e)]E(z_e) + \mu_h[E(z_h)]E(z_h)$$
$$\approx \{\mu_e[E(z_0)] + \mu_h[E(z_0)]\}E(z_0).$$
$$i_h(z; t \to t_h) = \sum_{i=1}^{n} a_i \nabla U_i \approx \frac{ne}{i}(\mu_i + \mu_i)E(z_i)$$

$$i_q(z;t \to t_0) = \sum_q q \vec{v}_q \nabla U_w \approx \frac{ne}{d} (\mu_e + \mu_h) E(z)$$



Not as expected with certain laser

E field in LGAD - Suyu Xiao

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Field measurement: diffusion profile

- Use the expand of carrier cluster
- Utilize information of field intensity along carrier path
- Novally designed for LGAD!

$$\begin{split} N &= N_0 * \frac{1}{\sqrt{2\pi\sigma_D^2}} \exp\left[-\frac{(z-\mu Et)^2}{2\sigma_D^2}\right] \\ N(z,t) &= \frac{1}{\sqrt{2\pi\tau^2}} \exp\left(-\frac{t^2}{2\tau^2}\right) * \frac{\sum N}{\sqrt{2\pi\sigma^2}} \exp\left[-\frac{(z-z_0-\mu Et)^2}{2\sigma^2}\right], \\ \frac{d\sigma^2}{dt} &= \frac{k_B T}{q} \mu + 2\sigma^2 \frac{d(\mu E)}{dz}. \\ \sigma^2 &= \frac{(\mu_e E_e)^2}{(\mu_i E_i)^2} \left[\int_{z_i}^{z_e} \frac{k_B T}{q} \frac{dz}{E} \frac{(\mu_i E_i)^2}{(\mu E)^2} + \sigma_0^2\right], \quad \frac{di_q}{dt}\Big|_{max} = \frac{k_2 \sum N}{\sqrt{\tau^2 v_e^2 + \sigma^2}}, \end{split}$$



https://arxiv.org/abs/2302.10020

(b) Diffusion profile of LGAD. The dashed box represents a preferred range that excludes the effect of the non-Gaussian shape of the carrier cluster.

Same trend & close value

SICAR SiC+LGAD



- SICAR(SiC with gain layer) fabricated by RASER Team, using the facilities at Institute of Semiconductors, Chinese Academy of Sciences
- CV curve shows the depletion of gain layer, dark current $\sim 10^{-7}$ A
- 20mV trigger for beta test(⁹⁰Sr), rise time ~0.5ns

Si strip detector and experimental set-up



Si strip detector



Layout of beta test set-up

- ITk mini sensor
- Alibava system classic for electrical readout
 - \rightarrow charge information

ITk mini sensor					
n+	1.0*10 ¹⁹ cm ⁻³	1 um			
р	$3.2*10^{12} \text{ cm}^{-3}$	300 um			
backside	$1.0*10^{15} \text{cm}^{-3}$	5 um			

Charge collection of Si strip



- 2D field solved in RASER by DEVSIM
- Charge collection simulation of non-irradiated detector shows good agreement with experiment.
- Charge collection decrease to ~50% with irradiation of 1.6×10^{15} neq/cm²

Irradiation in RASER



- Free carriers generated from leakage current and trapped by deep level defects, changing the electric field distribution
- Total effective space charge negative at n+ contact and positive at p+ contact, causing double peak electric field
- Carriers trapped by deep level defects, signal depressed

Irradiation in RASER



 Considering double peak and trapping time, charge collection simulation is closed to data at irradiation dose of 1.0×10¹⁵ neq/cm² and 1.6×10¹⁵ neq/cm²

SICAR strip



SICAR strip stucture

- SICAR strip is possible based on previous Si strip study
- Epitaxy wafer same as SICAR, electrodes will be fabricated soon. SiC strip(without gain layer) will also be fabricated.
- 1D spatial information

Circular SICAR with graphene



- SICAR with circular electrodes avoid the metal effect, graphene will help carriers movement.
- Circular SICAR without graphene fabricated, behaves bad on IV&CV.
- Circular SiC will be produced for comparison.

SiC planar detector



- SiC planar detector fabricated from Nanjing University.
- Considering contribution from trapping time, waveform from RASER simulation is close to data.

SiC irradiation



- Trapping time and log(irradiation dose) show good linear distribution.
- Charge collection curve simulated in RASER is consistent with experiment. 100% is set at 1000V of non-irradiated case.

SICAR pixel and BJT



Layout of SICAR array

- Based on the SICAR array we have now, pixel study is possible.
- 2D spatial information
- AC-coupled SICAR pixel will be designed, in order to get better spatial resolution.



Sketch of SICAR BJT integrated sensor

- Pre-amp and main amplifier induce noise
- Integrating BJT with SICAR, noise will be depressed and timing resolution will be improved.

Summary and Plan

- Propose diffusion profile method for electric field in Si LGAD
- Simulate Si strip and SiC planar detector and irradiation effect

Electric field and irradiation of SICAR

Development in SICAR strip and pixel

□ More structure: circular SICAR with graphene, SICAR BJT...

Thanks for your attention.





Back-up

Strip irradiation

• The proportion of accumulated electrons in defects:

•
$$f_t = \frac{n_t}{N_t - n_t} = \frac{c_n n + e_p}{c_n n + e_n + c_p p + e_p}$$

- The generation rate of accumulated charge carriers in deep level defects:
 - $G_n = N_t f_t e_n$ $G_p = N_t (1 f_t) e_p$
- Carrier concentration in deep level defects:
 - $n(x) = p(x) = \frac{J}{e < v_{th} > v_{th}}$
- Effective space charge concentration:
 - $N_{eff} = N_{sh} + (1 f_t)N_{DD} f_t N_{DA}$
- Capture time of electrons and holes:

•
$$\frac{1}{\tau_{eff,e}} = \sum_{defects} c_n (1 - f_t) N_t$$

•
$$\frac{1}{\tau_{eff,h}} = \sum_{defects} c_p f_t N_t$$

Туре	Energ[eV]	$g_{int}[cm^{-1}]$	$\sigma_e[cm^2]$	$\sigma_h[cm^2]$
Acceptor	$E_{c} - 0.42$	0.48	1e-15	1e-14
Acceptor	$E_{c} - 0.46$	0.18	7e-15	7e-14
Donor	$E_{v} + 0.36$	0.05	3.23e-13	3.23e-14
Donor	$E_{v} - 0.48$	0.64	4.1e-15	1.9e-16